(c) SiO$_2$ re-deposition

(d) over-etch

Fig. 3.6 SEM photos of the sidewall gate process (2)
Fig. 3.7 SEM photos of the sidewall T-shaped gate before and after gate metal deposition.

(a) Before gate metal deposited

(b) After gate metal deposited

Fig. 3.7 SEM photos of the sidewall T-shaped gate before and after gate metal deposition
Fig. 3.8 Process flow of airbridge (1)
Fig. 3.8 Process flow of airbridge (2)